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SU9000Ⅱ / SU8700 / SU8600 / SU7000 / SU5000 / SU3900SE / SU3800SE

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Model	 Ultra-high Resolution Scanning Electron Microscope SU9000Ⅱ	 Ultra-high Resolution Schottky Scanning Electron Microscope SU8700	 Ultra-high Resolution Field-emission Scanning Electron Microscope SU8600	 Ultra-High-Resolution anning Electron Microscope SU7000	 Schottky Field Emission Scanning Electron Microscope SU5000	 High Resolution Schottky Scanning Electron Microscope SU3900SE/SE Plus	 High Resolution Schottky Scanning Electron Microscope SU3800SE/SE Plus
Magnification	80 to 3,000,000 x	20 to 2,000,000 x	20 to 2,000,000 x	20 to 2,000,000 x	10 to 600,000 x	5 to 600,000 x	
Resolution	0.34 nm at 30 kV (STEM)* 0.4 nm at 30 kV (SE) 1.0 nm at 1 kV (SE) 0.7 nm at 1 kV (SE with deceleration)*	0.6 nm at 15 kV (SE) 0.8 nm at 1 kV (SE) 0.9 nm at 0.3 kV (SE)	0.6 nm at 15 kV (SE) 0.7 nm at 1 kV (SE with deceleration)	0.8 nm at 15 kV (SE) 0.9 nm at 1 kV (SE)	1.2 nm at 30 kV (SE) 3.0 nm at 1 kV (SE) 2.0 nm at 1 kV (SE with deceleration)* 1.6 nm at 1 kV (SE with EX deceleration)* 3.0 nm at 15 kV (BSE, variable pressure mode*)	0.9 nm@30 kV 2.5 nm@1 kV 1.6 nm@1 kV (SE with deceleration / available only for SE Plus specification)*	
Electron source	Cold cathode field emitter	ZrO / W Schottky emitter	Cold cathode field emitter	ZrO / W Schottky emitter		ZrO / W Schottky emitter	
Accelerating voltage	0.5 to 30 kV	0.1 to 30 kV	0.5 to 30 kV	0.1 to 30 kV	0.5 to 30 kV	0.5 kV～30 kV	
Landing voltage	0.1 to 2 kV*	0.01 to 7 kV (SE with deceleration)	0.01 to 20 kV (SE with deceleration)	0.01 to 7 kV*	0.1 to 20 kV*	0.1 kV～2 kV (SE with deceleration/ available only for SE Plus specification)*	
Variable pressure	—	5 to 300 Pa*	—	5 to 300 Pa*	10 to 300 Pa*	6 to 150 Pa	
Sample stage traverse	Side entry goniometer stage X：±4.0 mm Y：±2.0 mm Z：±0.3 mm T：±40°	5-axis motorized stage X：0 to 110 mm Y：0 to 110 mm Z：1.5 to 40 mm T：-5 to 70° R：360°		5-axis motorized stage X：0 to 135 mm Y：0 to 100 mm Z：1.5 to 40 mm T：-5 to 70° R：360°	5-axis motorized stage X：0 to 100 mm Y：0 to 50 mm Z：3 to 65 mm T：-20 to 90° R：360°	5-axis motorized stage X：0 to 150 mm Y：0 to 150 mm Z：3 to 85 mm T：-20 to 90° R：360°	5-axis motorized stage X：0 to 100 mm Y：0 to 50 mm Z：3 to 65 mm T：-20 to 90° R：360°
Maximum sample size	Bulk Holder：5.0 mm x 9.5 mm Cross-section Holder：2.0 mm x 6.5 mm	150 mm (in diameter)		200 mm (in diameter)		300 mm (in diameter)	200 mm (in diameter)
Maximum sample thickness	Bulk Holder：3.5 mm Cross-section Holder：5.0 mm	36 mm (with holder)		80 mm (with holder)		130 mm (WD=10 mm)	80 mm (WD=10 mm)
Signal detector	Secondary electron detector (SED) TOP detector* BF/DF Duo-STEM detector* Energy dispersive X-ray detector*	Upper detector (UD) Lower detector (LD) Middle detector (MD)* Semiconductor type BSE detector (PD-BSED)* Ultra Variable-Pressure detector(UVD)* TE detector*	Upper detector (UD) (with SE/BSE signal mixing function) Lower detector (LD) Top detector (TD)* In-Column Middle detector (IMD)* Out-Column Crystal Type BSED (OCD)* Semiconductor type BSE detector (PD-BSED)* Cathodoluminescence detector (CLD)* TE detector*	Upper detector (UD) Middle detector (MD) Lower detector (LD) Semiconductor type BSE detector (PD-BSED)* Ultra Variable-Pressure Detector (UVD)* TE detector*	Secondary electron detector (SED) TOP detector* Semiconductor type BSE detector (PD-BSED)* Ultra Variable pressure-Detector (UVD)* TE detector*	Secondary Electron Detector (SED) TOP detector (TD) (available only for SE Plus specification)* 4+1-segment Semiconductor Type Backscattered Electron Detector (BSED) Ultra Variable Pressure Detector (UVD)*	
Analysis system	Energy Dispersive X-ray Spectrometer (EDS)* Electron Energy Loss Spectrometer (EELS)* Electron Diffraction*	Energy Dispersive X-ray Spectrometer (EDS)* Electron Backscatter Diffraction (EBSD)*		Energy Dispersive X-ray Spectrometer (EDS)* Electron Backscatter Diffraction (EBSD)* Wavelength Dispersive X-ray Spectrometer (WDS)*		Energy Dispersive X-ray Spectrometer (EDS)* Electron Backscatter Diffraction (EBSD)*	

*option

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